IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application for:

Kevin J. Lee Examiner: Lois L. Zheng

Serial No. 10/808,763 Art Unit: 1742

Filed: March 24, 2004

For: CONTROLLED POTENTIAL ANODIC ETCHING

PROCESS FOR THE SELECTIVE REMOVAL OF

CONDUCTIVE THIN FILMS

SUBMISSION PURSUANT TO 37 C.F.R. § 1.114

Mail Stop RCE Commissioner for Patents P.O. Box 1450 Alexandria, Virginia 22313-1450

Dear Ma'am:

Pursuant to 37 CFR § 1.114, Applicants submit the following amendment and remarks in addition to the fee set forth in 37 CFR § 1.17(e).

Amendments to the Claims are reflected in the listing of claims and begins on page 2 of this response.

Remarks/Arguments begin on page 3 of this response.